

Fig.1

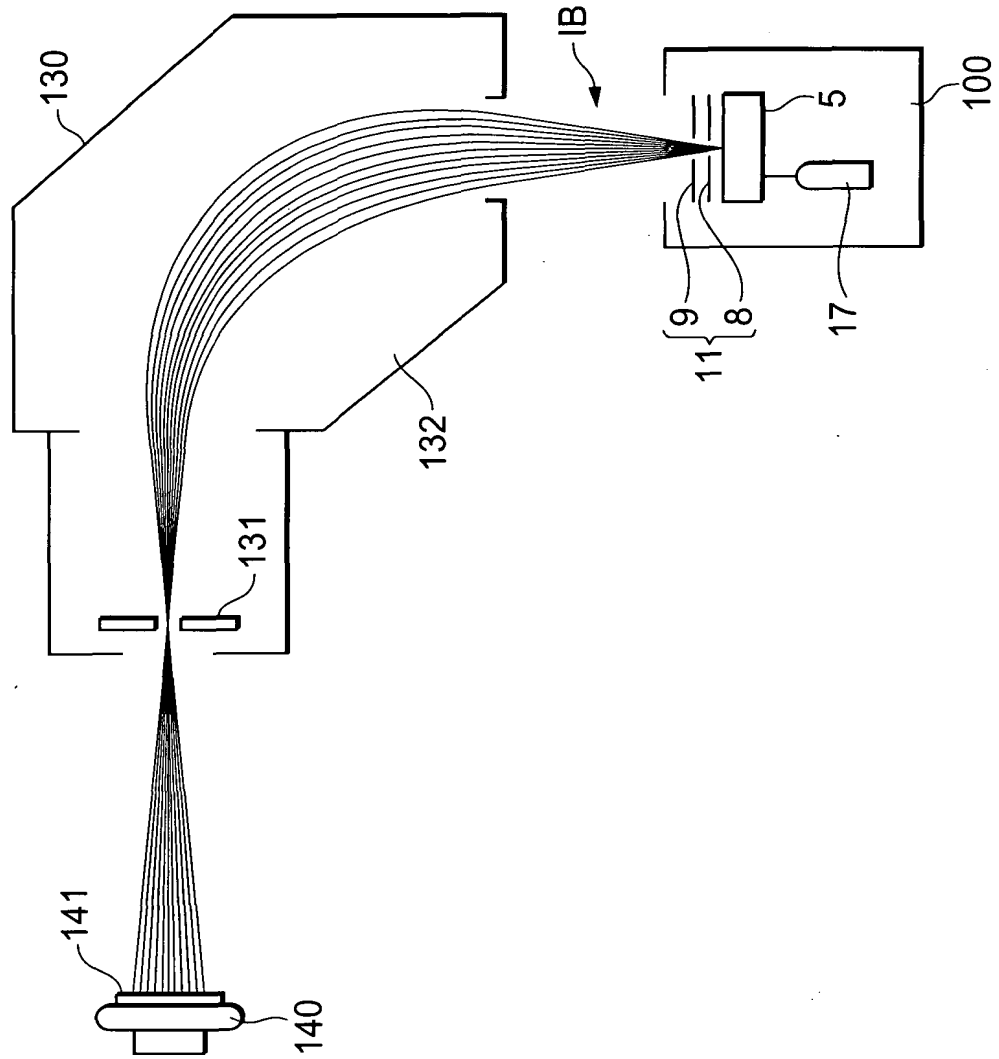


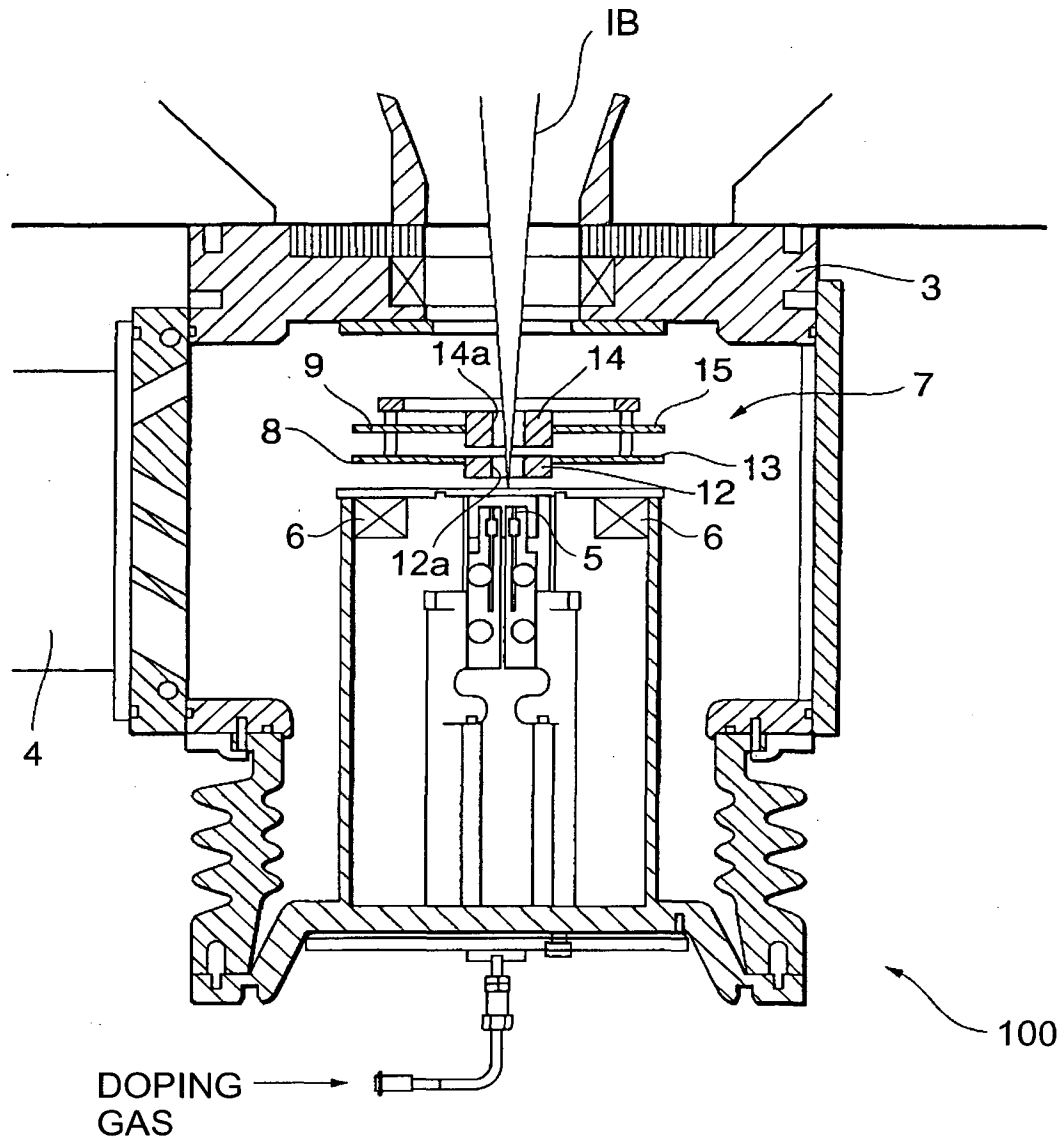
Fig.2

Fig.3

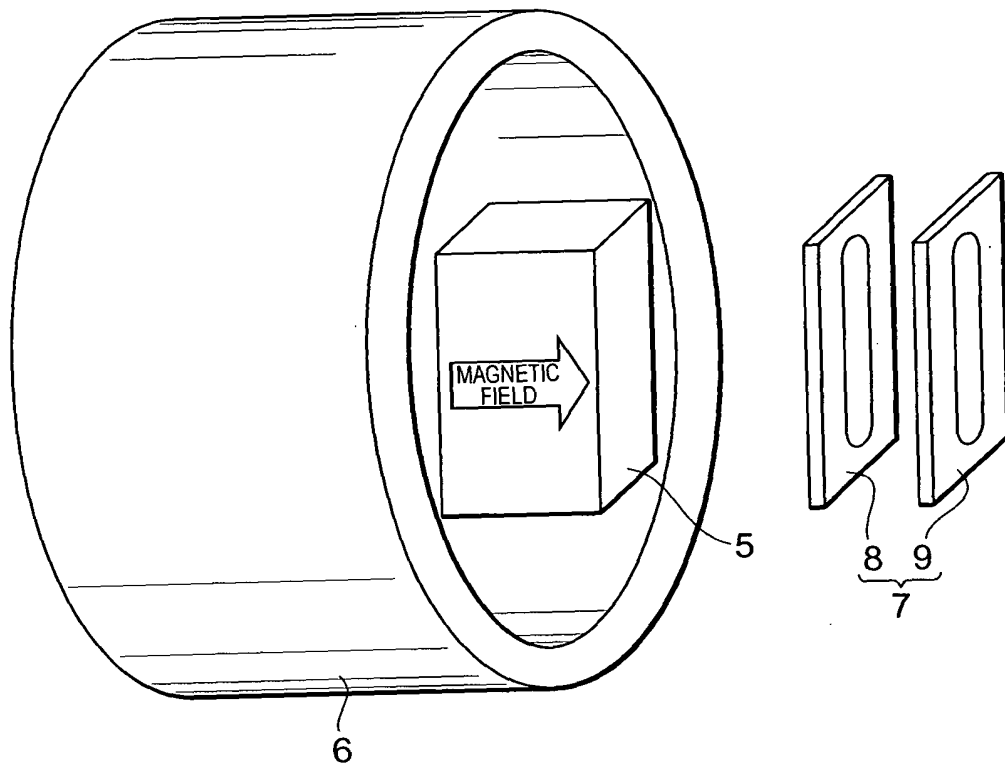
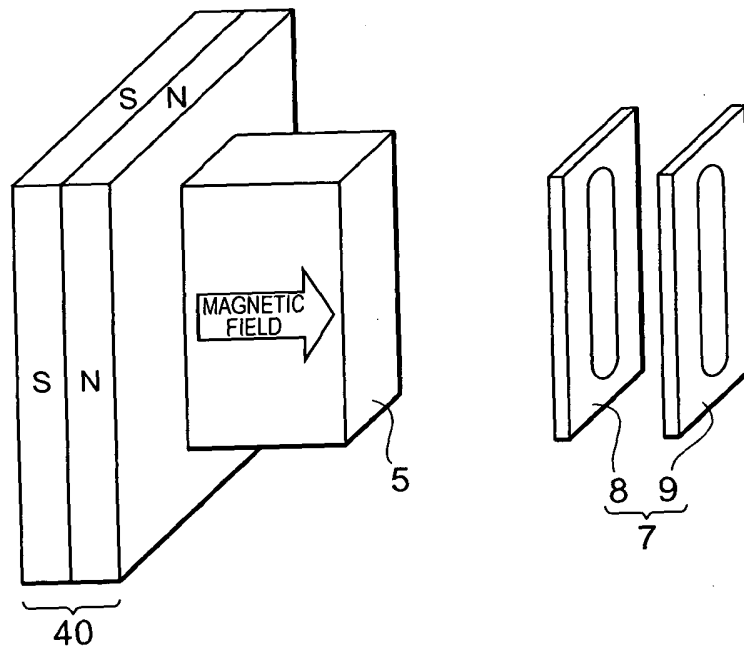


Fig.4



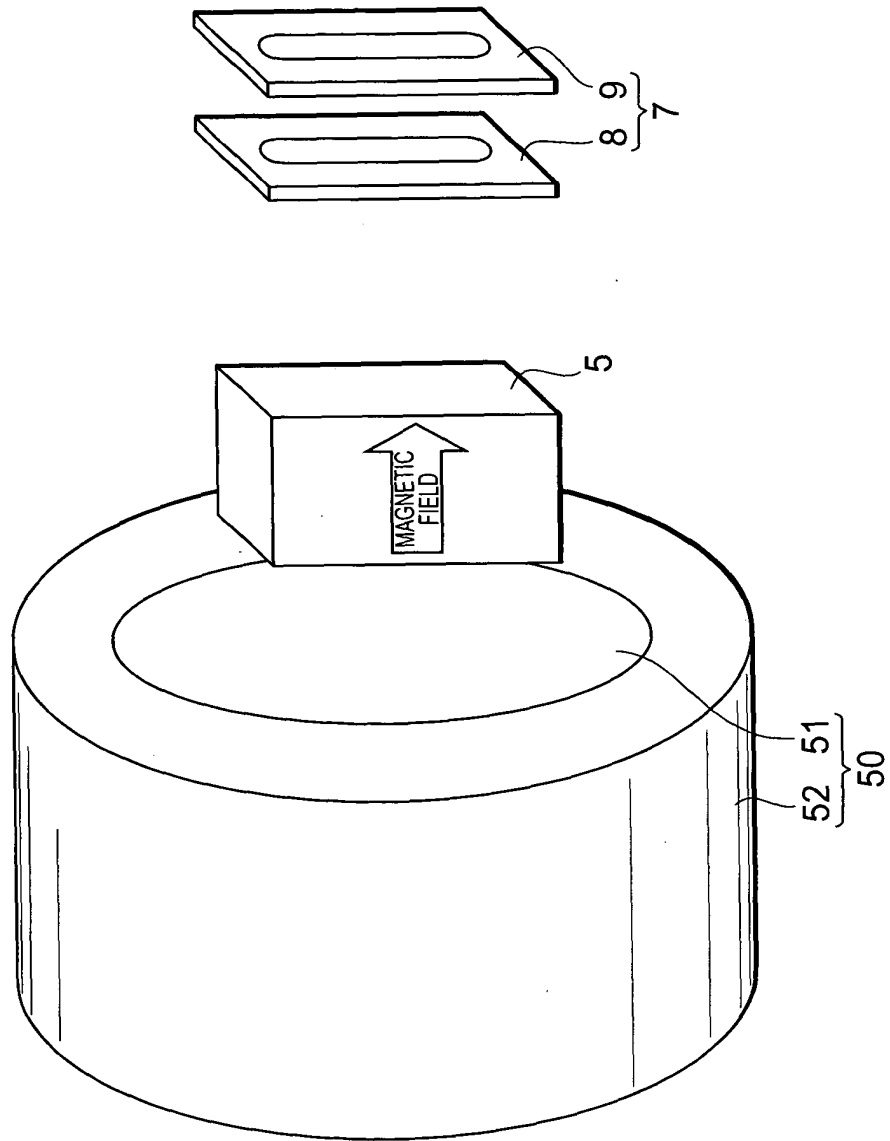
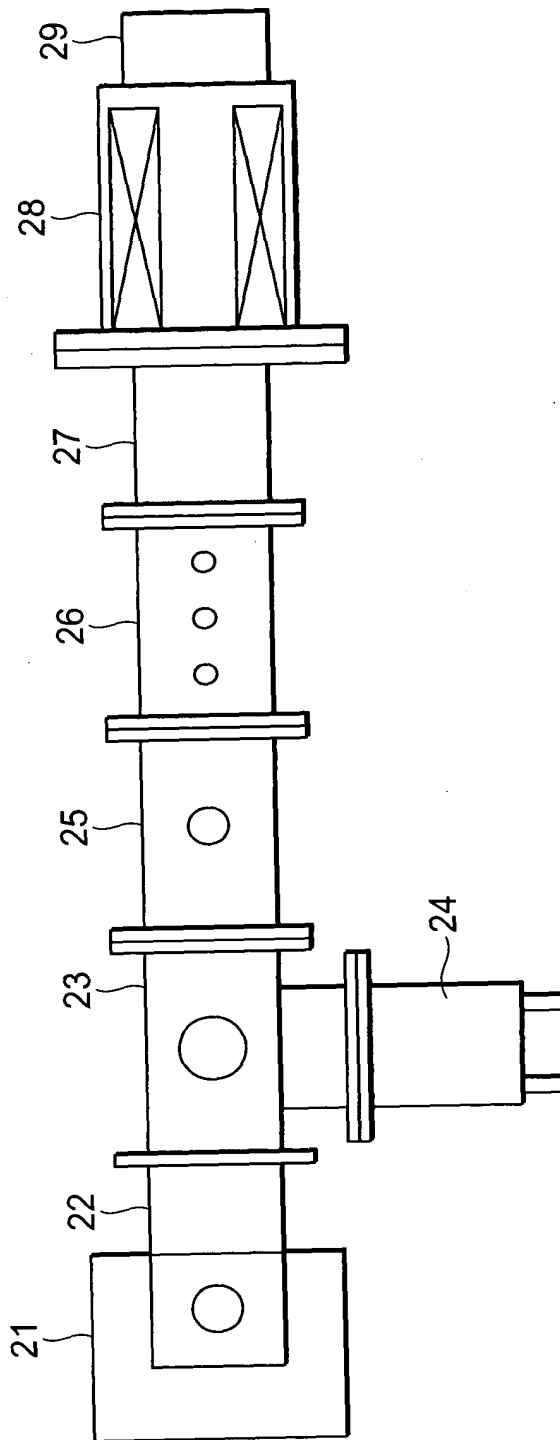


Fig. 5

6/8

Fig.6



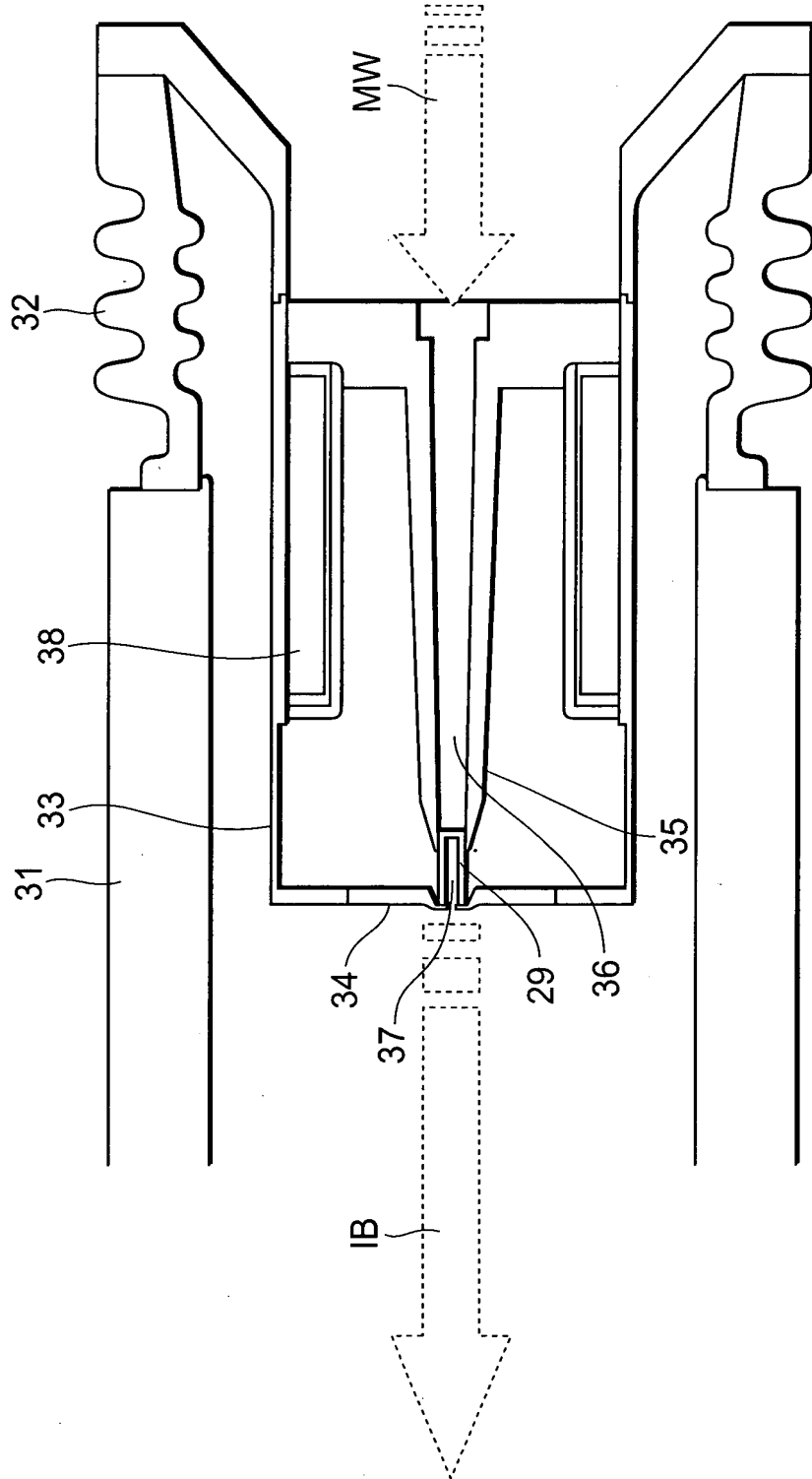


Fig. 7

ATTY DKT. No.:	SOEI/0057	CONF. No.:	UNKNOWN
U.S. SERIAL No.:	UNASSIGNED		
FILED:	HEREWITH		
APPLICANT:	APPLIED MATERIALS, INC.		
TITLE:	ION IMPLANTATION METHOD, SOI WAFER MANUFACTURING METHOD		
INVENTOR:	ITO, ET AL.		

Fig.8A

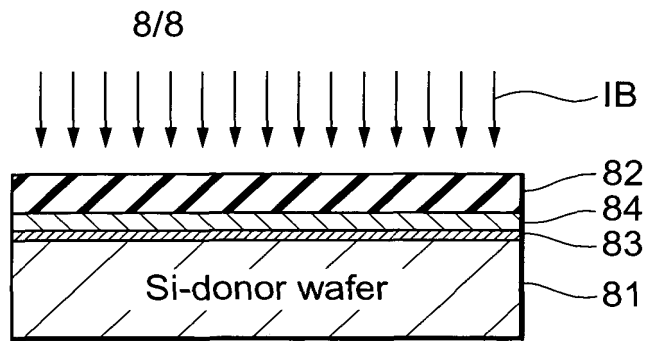


Fig.8B

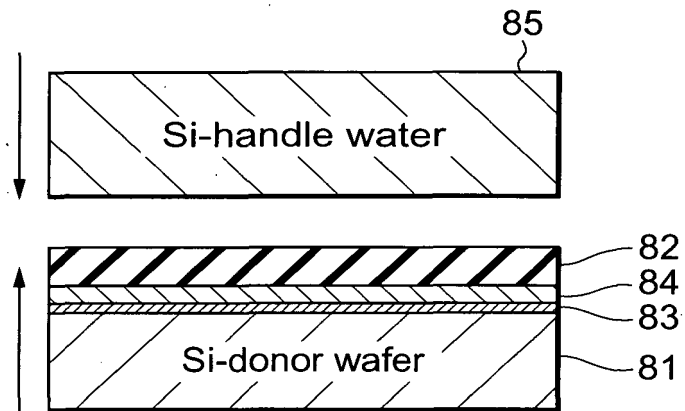


Fig.8C

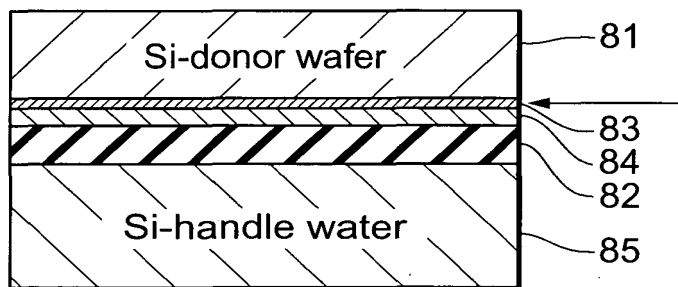


Fig.8D

